



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 5686**
Mitsuo SAITOH et al. : Docket No. 2003_1228A
Serial No. 10/649,670 : Group Art Unit 1763
Filed August 28, 2003 : Examiner Allan W. Olsen

PLASMA PROCESSING METHOD
AND APPARATUS

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Restriction Requirement of August 12, 2005, Applicants hereby elect Group I, which is drawn to a plasma processing method and is embodied by claims 1-8.

Having made the required election, a full examination on the merits of the elected group is requested.

Respectfully submitted,

Mitsuo SAITOH et al.

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